

Production solutions for high-performance optics – from sample to high volume



June 2023



Who we are

- Since 2001 pioneers in Nanoimprint lithography
- We combine several technologies developed at well-known Research Lab (Natlab) in Eindhoven
 - Method to create nanostructures
 - Inorganic (sol-gel) materials
 - >100 years of know-how in high-volume manufacturing equipment
 - Machine vision expertise







Equipment, material and processes for production of high precision optics

- High-volume production solutions delivered for lasers, wiregrid polarizers, metalenses and AR waveguides
- Spin-out of Philips supported by a strong consortium of European funding partners



Transforming surface into function

SCIL Nanoimprint solutions

Nanoimprint production solutions for wafer-level optics

• Wafers up to 300mm

• Feature sizes down to 10 nanometers

Positioning accuracy below
1 micrometer

• Stamp life-time > 500 imprints

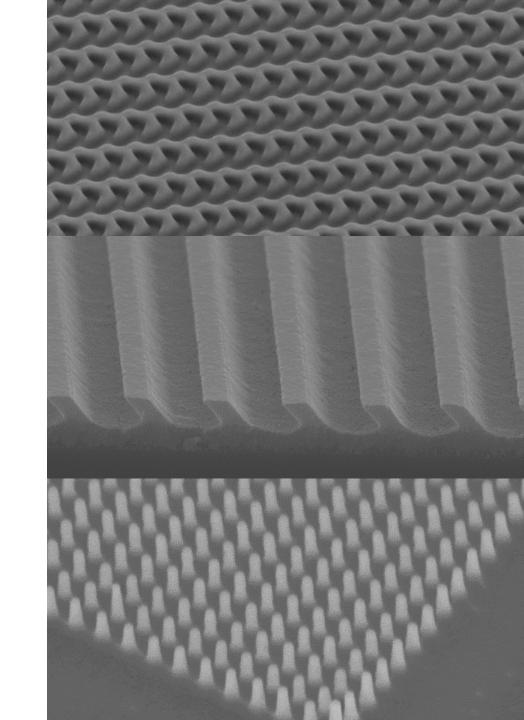
• Patent families 30

Large range of fully inorganic imprint materials with excellent optical properties

 Works with industry available UV-curable organic imprint materials

On any material, from glass to sapphire to silicon





Large variety of applications in growth markets

Mobile devices

Smart Glasses

Automotive

Medical

Other



- Camera lenses (metalenses)
- Sapphire camera covers
- MicroLED displays
- Face recognition sensors
- AR Waveguides
- MicroLED projectors
- 3D sensors
- 3D sensors
- Front-lights
- Light carpets
- Head-up displays
- Biosensors
- Medical imaging
- Lasers
- LED
- Solar
- Quantum computing
- Integrated photonics



High-volume production solutions for wafer patterning

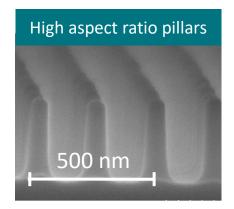


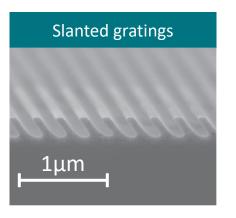


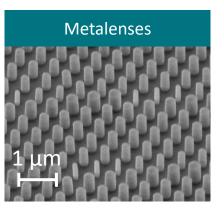
- Consumables
- Services
 - Process development
 - Sample and pilot production
 - Maintenance and support

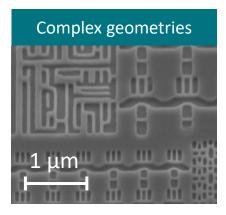


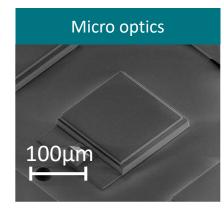
From nano-to micro structures











From R&D to volume production





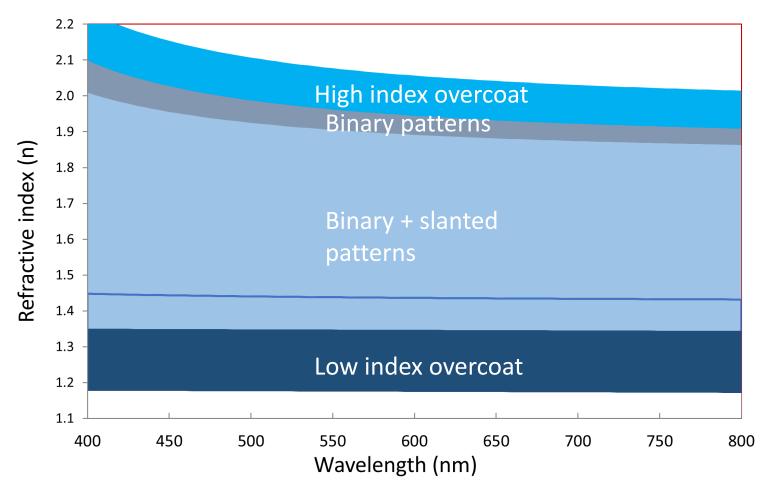






Imprint materials - full range in refractive index

- Directly patterning optical materials
- All resist types are fully inorganic
 - Index range n=1.17 to 2.2
 - Increased slant index to n=1.93
 - Non-absorbing down to λ ~**360**nm
 - Temperature stable >400°C
 - Non-yellowing
- Low shrinkage: 5-8%
- Applications:
 - Augmented Reality
 - Meta-surfaces
 - Etch masks
- Key figure or merit: nm-reproducible features



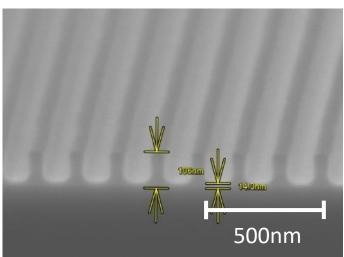


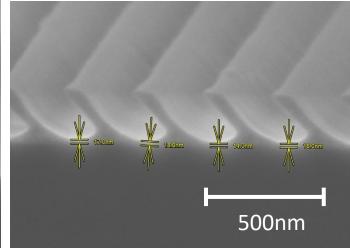
Binary and slanted gratings in high index inorganic material

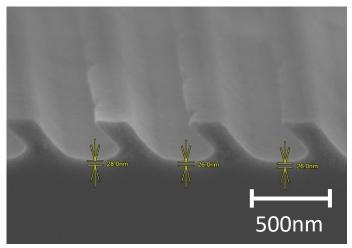
- n=1.75
- RLT below 20nm
- Slant gratings in all directions possible in the same imprint
- Very low to no haze

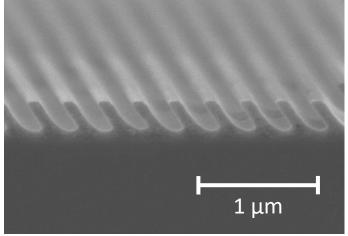
- n=1.93
- RLT below 30nm demonstrated (expect to reach RLT <20nm)
- Slant gratings in all directions possible in the same imprint
- Very low to no haze



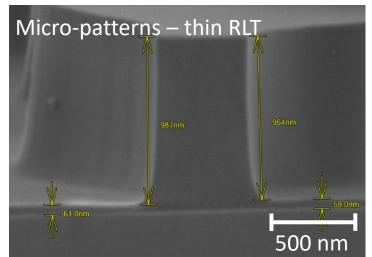


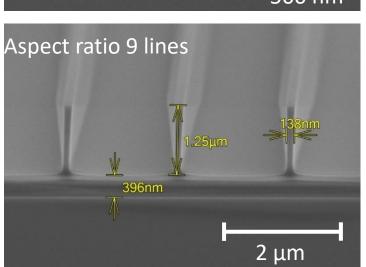


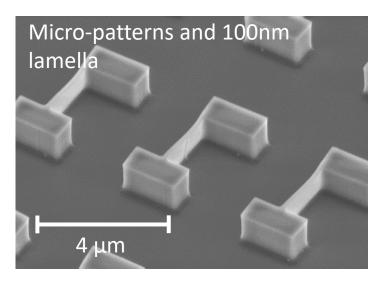


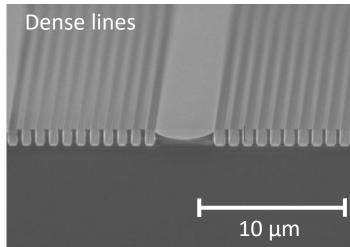


Variety of micro patterns, direct replication into NanoGlass









- High aspect ratio patterns
- Thin residual layer



How we work

- We develop the right imprint process for the requirements of our customers
- Combined with optimized equipment and consumables
- We produce samples for qualification purposes
- When ready we deliver the production equipment and transfer the SCIL imprint process to the production site of our customer

Fast development cycles and a cost efficient and reliable solution that works





